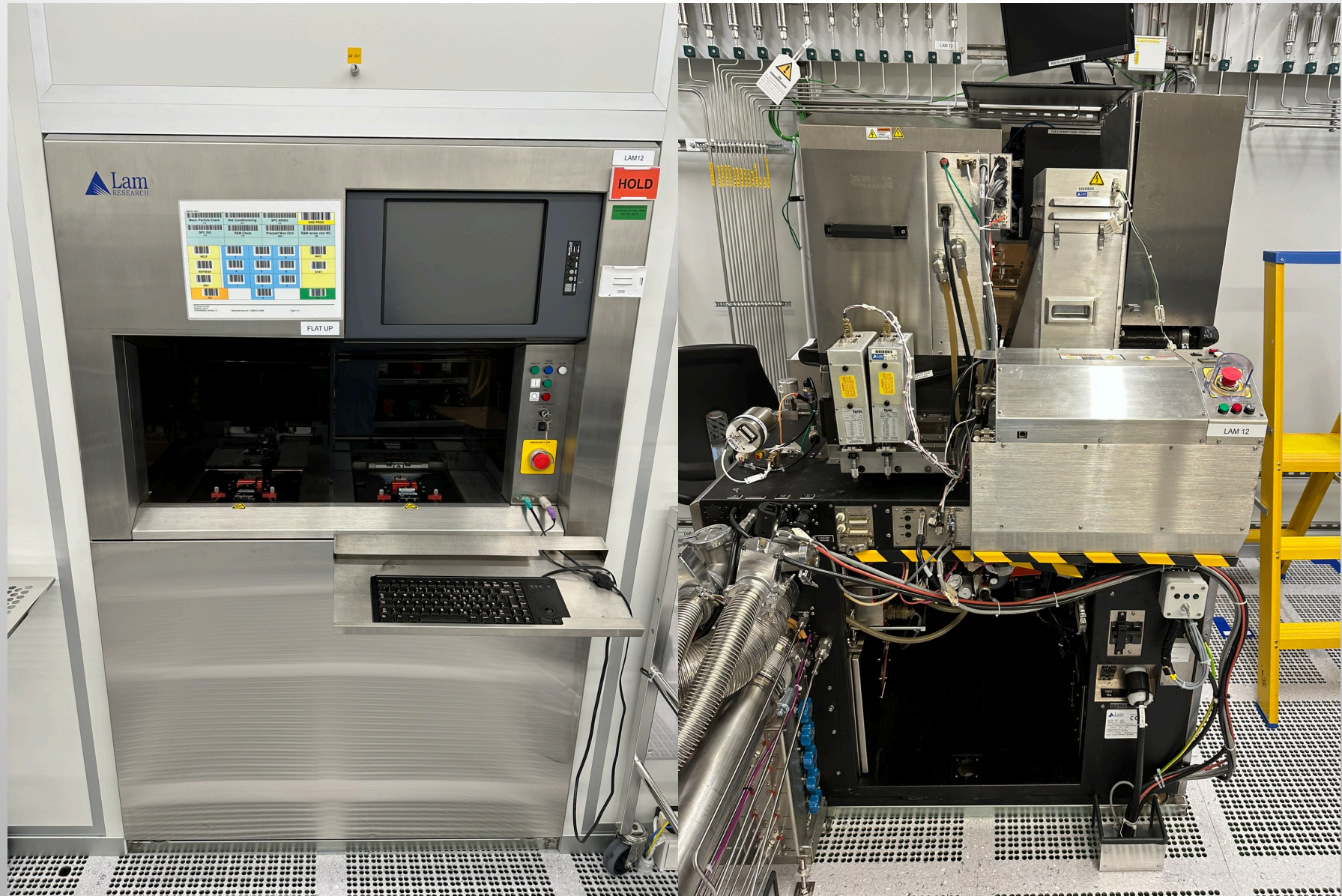




LAM Research
4520i Oxide Etch 150mm Configuration
SN 3812

LAM Research
4520i Oxide Etch SN 3812



www.Solutions-on-Silicon.com

LAM Research
4520i Oxide Etch SN 2812



LAM Research 4520i Oxide Etch SN 3812



Tool Model : 4520i
Tool Serial Number : 3812
Bulkhead system mount w/tunnel covers
Hine 38A open cassette Send/Receive indexers
Software Version: Envision
Oxide etcher, 6"
Clamp type ESC
RF power Rack AE PDW2200 RF Generator
AE Isotropic Module
Chiller Unit (none/To customer Spec)
AC Rack AC Power Distribution
Moving gap
Back Helium Colling
Main Power 208V, 3 Phase, 5Wire, 175A, 60/
Hine 38A open cassePe Send/Receive indexers
Belt driven load station
Standard load station shuttle spatula
Upper chamber gap drive encoder
Dip PCB for RF power tuning
Aluminum upper chamber electrode

6" Clamp lower chamber electrode
Single lower chamber endpoint detector (405/520nm) Non-
-heated endpoint window
Low pressure chamber manifold
HPS valve for chamber isolation
AC--2 chamber pressure control
Lower chamber RGA port
8 -- Gas box Orbital gas box
Gas 1: AR 500sccm
Gas 2: CF4 50 sccm
Gas 3: CHF3 50 sccm
Gas 4: CF4 200 sccm
Gas 5: O2 50 sccm
Gas 6: N2 50 sccm
Gas 7 HE 500 sccm
Gas 8: NF3 500sccm
UPC: He (50 sccm)
AC input box for AC power inlet

Solutions on Silicon BV

Your service partner for LAM Research Equipment

- **Equipment Support**
PM, CM, Trouble shooting, Upgrading, Training and Onsite Service Contracts
- **Process Support**
Process design, Improvement, Fab-to-Fab Transfer and Integration
- **Refurbishment**
From custom to complete refurbishment
- **Relocation**
Auditing, Fingerprinting, Decommissioning, Installation, Acceptance
- **Materials**
Supplier of first class second source materials

